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# XP818: ELM Mitigation with Midplane Control Coils

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#### **NSTX Team Review**

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## Exploratory approach to finding ELM mitigation solution with midplane non-axisymmetric coils

- Goal
  - Demonstration of ELM mitigation with NSTX midplane RWM coil set
- Approach
  - Target development
    - (i) low  $q_{95}$  < 6; (ii) swept  $q_{95}$  to insure mitigation not missed due to resonance ; (iii) high  $q_{95}$  > 8
  - □ Application of DC fields (broader *n* spectrum, new 2008 capabilities)
    - Past odd parity fields (n = 3, 1+3) operating on low  $q_{95}$  target
    - New even parity field (n = 2 (strong n = 4), 6) capability for 2008
    - New combined odd/even parity (present favorite n = 2 + 3)
  - Application of AC fields
    - Using either/both odd and even parity fields; co/ctr propagation
       ELM mitigation through effects on edge plasma profiles
    - Feedback on *n* = 1
      - □ May be useful for giant ELMs, buildup detected by RWM  $B_r$  sensors

Repeat techniques showing most potential in low recycling (post-LITER)

### New non-axisymmetric field capability allows new combinations for ELM mitigation



 n = 2+3 field can produce Chirikov overlap near the plasma edge at reasonable SPA currents

Simulation: RWM coils (1-4) 0.5 kA, (2-6) 0.5 kA, (3-5) 1.5 kA

#### ELM mitigation by DC fields might be resonant effect



DIII-D indicates narrow q window for ELM mitigation

• Should scan  $q_{95}$  to insure that window is not missed

## Planned mixed even/odd parity fields require nondiametrically-opposed coil pairs



odd parity fields alone are standard anti-series connection

even parity fields alone are "new" standard series connection



## XP818 ELM Mitigation - Run plan

Task	Numbe	r of Shots
1) Create target plasmas		
A) Create q95 < 6 target: (generate at least 10 ELMs with approximately even spacing)		
( <i>q</i> 95 ~ 5.5 is adequate)		
- Use shot 124349 as setup shot, ( <i>Ip</i> = 0.8 MA, <i>Bt</i> = 0.5 T), change NBI source C to 1 MW unmodulated		0
Deine Inte 0.0 MA: change Bt to 0.45T, then 0.40T		2
- Raise ip to 0.9 MA, change Bl to 0.451, then 0.401		3
- II q95 > 6 and insumclem ELIVIS, perform startup optimizations as per 5. Menard		(0)
R) Croate g05 romp torget		(0)
B) Create $qg$ famp target created in step (1A). In flat tep to 0.7 MA, remaining up		
- Start from low q95 target created in step (TA), ip hat-top to 0.7 MA, ramping up		٨
$_{-}$ if plasma drops out of H-mode, start in ramp from 1.0 MA ramping to 0.7 MA		+ (2)
- very <i>Bt</i> to change range of <i>a</i> ramp (optional)		(2)
c) Create $a95 > 8$ target		(2)
- Use shot 124349 as setup shot $(I_{D} = 0.8 \text{ MA} Bt = 0.5 \text{ T})$ change NBI source C to 1 MW unmodulated		
- Drop $I_D$ to 0.7 MA: tweak to 0.75 MA if desired		2
2) Attempt ELM mitigation with non-axisymmetric fields under normal recycling conditions		
- <u>DC fields</u> :		
A) Apply $n = 3$ field configuration; vary amplitude from 1.5 kA		4
B) Apply $n = 3 + 1$ field configuration; vary amplitude from 1.0 kA, 0.5 kA		4
C) Apply $n = 2 + 3$ field configuration		
(start from RWM (1-4) 0.5kA, RWM (2,6) 0.5kA, RWM (3,5) 1.5 kA)		4
D) Apply $n = 2$ field configuration; vary amplitude from 1.5 kA		4
E) Apply $n = 6$ field configuration (primary field is $n = 0$ ); vary amplitude from 2.5 kA		3
- <u>AC fields (pre-programmed)</u> :		
F) Apply $n = 3$ ; vary f above/below ELM frequency; vary amplitude from 2.0 kA		4
G) Apply n = 1 (co-propagating); vary f above/below ELM frequency; vary amplitude		4
H) Apply $n = 1$ (ctr-propagating); vary f above/below ELM frequency; vary amplitude		4
- <u>AC fields (n = 1 feedback)</u> :		
I) $n = 1$ Br feedback: giant ELM target (e.g. 125271), vary (i) gain (ii) phase		6
3) Attempt ELM mitigation with non-axisymmetric fields under reduced recycling conditions		16
т	otol (optional);	64 (10)



Total (optional): 64 (12)

## XP818 ELM Mitigation – first "1/2" day run plan

Task Nu	umber of Shots
1) Create target plasmas	
A) Create q95 < 6 target: (generate at least 10 ELMs with approximately even spacing)	
( <i>q95</i> ~ 5.5 is adequate)	
- Use shot 124349 as setup shot, ( $Ip = 0.8$ MA, $Bt = 0.5$ T), change NBI source C to 1 MW unmod	ulated 2
- Raise <i>Ip</i> to 0.9 MA; vary Bt to 0.45T, then 0.40T	3
- If q95 > 6 and insufficient ELMs, perform startup optimization as per J. Menard to raise qmin.	(8)
B) Create <i>q95</i> ramp target	
- Start from low q95 target created in step (1A), Ip flat-top to 0.7 MA, ramping up	
to 1.0 MA; adjust eventual <i>Ip</i> flat-top if needed to create steady ELMs.	4
<ul> <li>If plasma drops out of H-mode, start Ip ramp from 1.0 MA ramping to 0.7 MA</li> </ul>	(2)
- Vary <i>Bt</i> to change range of <i>q</i> ramp (optional)	(2)
2) Attempt ELM mitigation with non-axisymmetric fields under normal recycling conditions	
- DC and AC fields:	
i) Apply DC $n = 3$ field configuration; vary amplitude from 1.5kA	2
ii) Apply AC $n = 3$ ; vary f above/below ELM frequency; vary amplitude	2
iii) Apply DC $n = 3 + 1$ field configuration; vary amplitude from 1.5kA	2
iv) Apply AC $n = 1$ (co-propagating); vary f above/below ELM frequency; vary amplitude	2
(optionally include $n = 3$ based on results from (iii) above)	

Total (optional): 17 (12)

